

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 118211		APPLICATION NO. New U.S. Patent Application <div style="font-size: 1.5em; font-family: cursive;">10/965, 197</div>	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT Mutsumi KIMURA		Group <div style="font-size: 1.5em; font-family: cursive;">2822</div>	
				FILING DATE January 28, 2004			

U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	

FOREIGN PATENT DOCUMENTS						
DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS		
<div style="font-size: 1.5em; font-family: cursive;">ms</div> 1	JP A 2001-282424 w/ abst & trans	10/12/2001	Japan			/
2	JP A 2001-282423 w/ abst & trans	10/12/2001	Japan			
3	JP A 2003-133708 w/ abst & trans	05/09/2003	Japan			
4	JP A 2003-77940 w/ abst & trans	03/14/2003	Japan			
5	JP A 2002-368282 w/ abst & trans	12/20/2002	Japan			
6	JP A 2002-343944 w/ abst & trans	11/29/2002	Japan			
7	JP A 2002-314123 w/ abst & trans	10/25/2002	Japan			
8	JP A 2002-314052 w/ abst & trans	10/25/2002	Japan			
9	JP A 2002-311858 w/ abst & trans	10/25/2002	Japan			
<div style="font-size: 1.5em; font-family: cursive;">ms</div> 10	JP A 2003-258210 w/ abst & trans	09/12/2003	Japan			

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)	

EXAMINER <div style="font-size: 1.5em; font-family: cursive;">Edy M. Seward</div>	DATE CONSIDERED <div style="font-size: 1.5em; font-family: cursive;">1ms</div>
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Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: January 28, 2004

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<div style="text-align: center;">OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)</div>							
SH	1	SHIMODA et al., "Surface Free Technology by Laser Annealing (SUFTLA)", IEEE, 1999, pp. 289-292.					
	2	UTSUNOMIYA et al., "Low Temperature Poly-Si TFTs on Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA™)", SID 00 DIGEST, 2000, pp. 916-919.					
	3	SHIMODA, "Future Trend of TFTs", Asia Display/IDW '01, pp. 327-330.					
JM	4	UTSUNOMIYA et al., "Low Temperature Poly-Si TFT-LCD Transferred onto Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA®)", Asia Display/IDW '01, pp. 339-342.					
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